




IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Attorney Docket No. MIC-58DV2)

Inventor: Zhang et al.) Examiner: Mohamedulla
Serial No. 09/722,400) Art Unit: 1756
Filing Date: November 27, 2000)
For: POLYIMIDE AS A MASK IN VAPOR HYDROGEN FLUORIDE
ETCHING

CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

I hereby certify that this correspondence, and any enclosures referenced herein, is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450

on 9/10, 2004.


Jody Begley

Assistant Commissioner for Patents
PO Box 1450
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AMENDMENT

In response to the Office Action of March 11, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.